

Substitute for form 1449A/PTO				<i>C mplete if Known</i>	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	Not Yet Assigned <i>10/719181</i>
(use as many sheets as necessary)				Filing Date	Herewith <i>11-20-03</i>
				First Name and Inventor	Miller, David
				Art Unit	Not Yet Assigned <i>2834</i>
				Examiner Name	Not Yet Assigned <i>T. Dougherty</i>
Sheet	1	of	3	Attorney Docket Number	019930-002820

U.S. PATENT DOCUMENTS+						
Examiner Initials*	Cite No. ¹	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear <i>Class Subclass</i>
		Number	Kind Code ² (if known)			
TMB	AA	5,414,540		05/09/95	Patel et al.	359 39
TMB	AB	5,917,625		06/29/99	Ogusu et al.	359 130
TMB	AC	5,999,672		12/07/99	Hunter et al.	385 37
TMO	AD	6,028,689		02/22/00	Michalicek et al.	359 224
TMO	AE	6,040,935		03/21/00	Michalicek	359 198
TMB	AF	6,097,859		08/01/00	Solgaard'	385 17
TMB	AG	6,108,471		08/22/00	Zhang et al.	385 37
TMB	AH	6,128,122		10/03/00	Drake et al.	359 224
TMB	AI	09/442,061		11/16/99	Weverka, et al.	— —
	AJ	US-				
	AK	US-				
	AL	US-				
	AM	US-				
	AN	US-				
	AO	US-				
	AP	US-				
	AQ	US-				
	AR	US-				
	AS	US-				
	AT	US-				

FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)			
	AU						<input type="checkbox"/>
	AV						<input type="checkbox"/>
	AW						<input type="checkbox"/>
	AX						<input type="checkbox"/>
	AY						<input type="checkbox"/>
	AZ						<input type="checkbox"/>
	BA						<input type="checkbox"/>
	BB						<input type="checkbox"/>

Examiner Signature	<i>Thomas Dougherty</i>	Date Considered	May 18, 2004
--------------------	-------------------------	-----------------	--------------

¹EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ²Applicant's unique citation designation number (optional). ³Kind Codes of U.S. Patent Documents at www.uspto.gov or MPEP 901.04. ⁴Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁵For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁶Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁷Applicant is to place a check mark here if English language Translation is attached.

60087181 v1

Substitute for form 1449B/PTO				Complete If Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					
(use as many sheets as necessary)					
Sheet	2	of	3		
Application Number	Not Yet Assigned 10/719,181				
Filing Date	Herewith 11-20-03				
First Named Inventor	Miller, David				
Art Unit	Not Yet Assigned 2834				
Examiner Name	Not Yet Assigned T. Dougherty				
Attorney Docket Number	019930-002820				

NON PATENT LITERATURE DOCUMENTS					
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			
TMW	BC	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110			
TMW	BD	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978			
TMW	BE	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992			
TMW	BF	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96			
TMW	BG	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999			
TMW	BH	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100			
TMW	BI	V. Kaajakari et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65			
TMW	BJ	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987			
TMW	BK	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 th May 1985			
TMW	BL	P. Phillippe et al., "Wavelength demultiplexer: using echelle gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985			
TMW	BM	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986			
TMW	BN	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998			
TMW	BO	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202			
TMW	BP	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem.Soc., Vol. 142; No. 6, June 1995			

Examiner Signature	<i>Thomas M. Dougherty</i>	Date Considered	May 18, 2004
--------------------	----------------------------	-----------------	--------------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

Substitute for form 1449B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	Not Yet Assigned <i>10/719,181</i>
(use as many sheets as necessary)				Filing Date	Herewith <i>11-20-03</i>
				First Named Inventor	Miller, David
				Art Unit	Not Yet Assigned <i>2834</i>
				Examiner Name	Not Yet Assigned <i>T. Dougherty</i>
Sheet	3	of	3	Attorney Docket Number	019930-002820

NON PATENT LITERATURE DOCUMENTS		
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
<i>TMD</i>		P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704
<i>TMD</i>		Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998
<i>TMH</i>		Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000

Examiner Signature	<i>Thomas M. Dougherty</i>	Date Considered	<i>May 18, 2004</i>
--------------------	----------------------------	-----------------	---------------------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.